

TruPlasma RF 1000 Air Series

Innovative 1000 W air cooled RF solution

Features

- Plug & Play solution
- Air cooled
- 100 kHz pulsing
- Smart auto frequency tuning
- Highly accurate arc management
- Patented Combineline Technology with true 50 Ω impedance
- Cable length independency



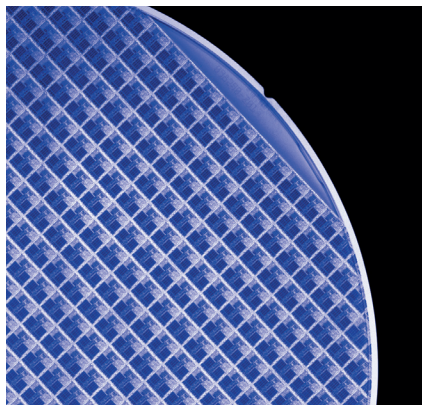
Applications

Semiconductor applications

- Chemical Vapor Deposition (CVD)
- Plasma activated CVD processes
- Etching applications
- Atomic layer deposition
- Atomic layer etch
- Reactive ion etching

Industrial coating applications

- Tool coating
- Hard coating
- Decorative coating



Benefits



Flexible adaption to the process



Extremely efficient and cost effective



Stable process power for best productivity and reproducibility



Substantial contribution to process homogeneity and highest uptime



TRUMPF Hüttinger
generating confidence

Technical data

RF output	TruPlasma RF 1000-0.6/13 Air	TruPlasma RF 1000-1/13 Air
Output power	0.6 kW	1 kW
Rated power	0.6 kW	1 kW
Nominal load impedance	50 Ω	50 Ω
Output frequency	13.56 MHz	13.56 MHz
Networking connection data		
Line voltage	190 – 240 V	190 – 240 V
Line frequency	50 – 60 Hz	50 – 60 Hz
Line input power	1.0 kVA	1.6 kVA
Power factor	> 0.9	> 0.9
Communication interfaces		
Sync interfaces	yes	yes
Analog / digital	yes	yes
RS 232 / RS 485	yes	yes
Profibus	no	no
EtherCAT	yes	yes
DeviceNet	yes	yes
Housing		
Weight	< 15 kg	< 15 kg
IP protection class	20	20
Cooling requirements		
Maximum water pressure	Air	Air
Minimum pressure difference	Air	Air
Minimum flow rate	Air	Air
Coolant temperature	Air	Air
General		
Overall efficiency	> 70 %	> 70 %
Certificates / standards	Semi S2, SEMI F47, UL, CE, RoHs	Semi S2, SEMI F47, UL, CE, RoHs
Ambient conditions		
Outside temperature	5 °C – 40 °C	5 °C – 40 °C
Humidity	5 % – 85 %	5 % – 85 %
Barometric pressure	79.5 kPa – 106 kPa	79.5 kPa – 106 kPa